



DOCKET NO: 240882US0

IN THE UNITED STATES PATENT & TRADEMARK OFFICE

IN RE APPLICATION OF

TOMOHISA KONNO, ET AL.

SERIAL NO: 10/626,521

FILED: JULY 25, 2003

FOR: AQUEOUS DISPERSION FOR
CHEMICAL MECHANICAL POLISHING
AND PRODUCTION PROCESS OF
SEMICONDUCTOR DEVICE

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: EXAMINER: RACHUBA, MAURINA T.

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: GROUP ART UNIT: 3723

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AMENDMENT AND REQUEST FOR RECONSIDERATION UNDER 37 CFR 1.114

COMMISSIONER FOR PATENTS
ALEXANDRIA, VIRGINIA 22313

SIR:

In response to the Office Action dated July 7, 2006, Applicants respectfully request reconsideration of the above-identified application in view of the following amendments and remarks:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Support for the Amendment begins on page 7 of this paper.

Request for Reconsideration begins on page 8 of this paper.